



PHOTON BEAM TRANSPORT SYSTEM AT FERMI@ELETTRA: MICROFOCUSING FEL BEAM WITH A K-B ACTIVE OPTICS SYSTEM

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FERMI@Elettra seeded FEL



FEL 1 from ~100 nm down to 20 nm - source distance (to spectrometer) 57.5 m Divergence $\sigma(\mu rad) = 1.25 \lambda(nm)$ - Source dimension = 60 μm (sigma)

FEL 2 from 20 nm down to ~4 nm - source distance (to spectrometer) 49.8 m Divergence $\sigma(\mu rad) = 1.5 \lambda(nm)$ - Source dimension = 123 μm (sigma)



K-B active optic system - DiProl



End-stations need high flux - great demagnification

. K-B system advantages

- Decoupling vertical and horizontal beam components
- Thick ellipsoidal mirrors with the great demagnification request are difficult to realize

K-B bendable system advantages

- Focalization of the 2 sources at different distance with the same couple of mirrors
- Improvement of the FEL beam wavefront

Holder K-B mirrors





K-B active optic system - DiProl

Profile surface characterization with Long Trace Profilometer

- LTP profile measurements 1mm step
- Best possible profile reached through the Adaptive Correction Tool software
- Measurements with Zygo interferometer and AFM rms under specifications (<3A spatial range $2\mu m$ 0.5mm)
- Proof of the system stability



K-B Horizontal mirror - residual surface profile

K-B active optic system - DiProl

Ray tracing simulations with Shadow code

K-B vertical mirror at best focus (+2mm to the nominal focus)

K-B horizontal mirror at best focus (-2mm to the nominal focus)

FWHM_{ray-tracing} = 18 μm

FWHM_{ray-tracing} = 10.5 µm



Focal spot measurements - DiProl Phosphorus screen and PMMA ablation

First phase

 rough angle alignment
 optimized mirror bending
 best spot achieved on Phosphorus screen FWHM_{32nm}=60x70 µm

Second phase

refine angle alignment

aoptimized mirror bending

best spot achieved:

Phosphorus screen FWHM_{32nm}=40x42 µm seen with PMMA ablation FWHM_{32nm}=15x26 µm

21 um



100 µm

15 um

PSF WITH FRESNEL DIFFRACTION

L. Raimondi, D. Spiga, SPIE Proc., 8147 (2010)

- PSF computation from surface metrology
- At any energy
- Approximations:
 - Work in scalar approximation
 - Computation using the meridional profiles (1Dimension)

Work in grazing incidence



PSF WITH FRESNEL DIFFRACTION L. Raimondi, D. Spiga, SPIE Proc., 8147 (2010)

SINGLE REFLECTION PARABOLA – ISOTROPIC SOURCE

ELECTRIC FIELD ON THE FOCAL PLANE OBTAINED BY THE CONSTRUCTIVE INTERFERENCE BETWEEN THE SPHERICAL WAVES GENERATED IN EACH POINTS OF THE MIRROR.

Kirchoff-Fresnel diffraction equation

$$U(P) = \frac{Ae^{ikr_0}}{r_0} \int \int_S \frac{e^{iks'}}{s'} K(\chi) dS'$$

$$PSF(x) = \frac{\Delta R}{f\lambda L^2} \left| \int_L e^{-i\frac{2\pi}{\lambda}(\sqrt{(x-x_{\rm p})^2 + z_{\rm p}^2} - z_{\rm p})} \, \mathrm{d}l \right|^2$$



PSF WITH FRESNEL DIFFRACTION L. Raimondi, D. Spiga, SPIE Proc., 8147 (2011)

Two or more reflections

Double reflection



Focal spot computation with Fresnel diffraction: FEL case



$$u(x,z) = \frac{\omega_0}{\omega} e^{\left[-j(kz-\Phi) - x^2(\frac{1}{\omega^2} + \frac{jk}{2R})\right]}$$

 $k = 2\pi / \lambda$ $\Phi = \arctan(\lambda z / \pi \omega_0^2)$

$$E_{\rm h}(x_{\rm h}, z_{\rm h}) = \frac{E_0 \Delta R}{L \sqrt{\lambda x_{\rm h}}} \int_{\rm f}^{\rm f+L} \left| \frac{x_{\rm p}}{\lambda} \sqrt{\frac{x_{\rm p}}{d_2}} e^{-\frac{2\pi i}{\lambda} (\overline{d_2} - z_{\rm p})} dz_{\rm p} \right|^2$$

$$PSF(x) = \frac{\Delta R}{E_0^2 f \lambda L^2} \left| E_h(x_h, z_h) e^{-i\frac{2\pi}{\lambda} (\sqrt{(x - x_h)^2 + z_h^2})} \right|^2$$

Focal spot simulations - DiProl

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32 nm wavelenght

K-B vertical best focus -2 mm from nominal FWHM_{32nm} = $5.8 \mu m$

K-B horizontal best focus 0 mm from nominal FWHM_{32nm} = $4.4 \mu m$

Suggestion - the system limit in terms of the spot size should be lower than shadow predictions

FEL 1 wavefront measurements



WAVEFRONT MEASUREMENTS BEFORE K-B SYSTEM

- FEL 1
- wavelength 32 nm
- distance from the source 90 m
- Gaussian intensity distribution
- nominal divergence 40 urad -> FWHM_{90m} = 8.5 mm

Wavefront = isophase surface

deformation from ideal shape (Gaussian beam) due to:

- Small instabilities of the Source
- photon transport optics

FEL 1 wavefront measurements



Focal spot measurements at DiProl end-station

Wavefront sensor measurements



FEL 1

- wavelength 32 nm
- measuring of Intensity and Wavefront at 1m out of nominal focus
- reconstruction of the spot in focal plane
- rms wavefront of best spot 12 nm





Focal spot measurements at DiProl end-station

Wavefront sensor measurements

Fresnel diffraction simulations

10

20

30

40



- FEL 1
- wavelength 32 nm
- diffraction limit spot-size at 32 nm FWHM = 4x5 µm
- Best spot-size measured FWHM = $5x8 \mu m$

- Spot-size simulated with ray-tracing $FWHM = 10.5x18 \mu m$
 - Spot-size simulated with Fresnel diffraction at the common best focus (-1mm from the nominal focus) FWHM = $5.2x7.7 \mu m$

CONCLUSIONS

- We performed surface profile characterization of the K-B bendable system mounted in the DiProl chamber with Long Trace Profilometer.
- We extended the Fresnel diffraction method to FEL applications non isotropic sources - focal spot given the best measured profile at LTP - FWHM = 4.4x7.7 µm
- We provided several measurement campaigns of K-B system focalization in the DiProi end-station, 40x42 µm on the P-screen 15x26 µm on PMMA
- We performed wavefront measurements of the FEL before K-B optics. The study of the focal spot degradation due to wavefront deformations is still under investigation
- Through a wavefront sensor we went further in the optimization of the mirror shape.
 Focal spot (reconstructed via software) FWHM = 5x8 µm
- From the comparison between simulations and measures we conclude that the focal spot in a FEL can now be predicted by using the Fresnel diffraction method.

People involved in this work:

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 PADReS

• F.Capotondi, E.Pedersoli, M.Kiskinova – DiProl

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THANKS FOR YOUR ATTENTION

Adaptive correction tool software



Adaptive Correction Tool

CH.	Voltage Correction
00	+2600.2 V
01	+1861.7 V

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PSF WITH FRESNEL DIFFRACTION Approximations:

Work in scalar approximation

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- Computation using the meridional profiles
 - The same slope errors along the azimuth result in an angular spread of rays smaller by a factor of tan2α
 - The X-ray scattering pattern in grazing incidence is 100-1000 times more extended in the incidence plane than in the perpendicular direction
 - Aperture diffraction resembles the diffraction pattern of a long, straight slit, which can be computed monodimensionally (visible in UV)

In order to prevent mirror under sampling:





PSF WITH FRESNEL DIFFRACTION

INTENSIRATIONS TRADE OF THE POCAL 2010 NE OBTAINED BY SUPERPOSING THE LINEAR DIFFRACTION FROM EVERY SLICE IN ITS MERIDIONAL PLANE

Kirchoff-Fresnel diffraction equation

$$U(P) = \frac{Ae^{ikr_0}}{r_0} \int \int_S \frac{e^{iks'}}{s'} K(\chi) dS'$$

$$E(x,y) = \int_{S} \frac{E_0}{d_2\lambda} \exp\left[-2i\pi \frac{d_1 + d_2}{\lambda}\right] \,\mathrm{d}^2s$$

$$E(x,y) = \frac{E_0}{f\lambda} \int_L e^{-i\frac{2\pi}{\lambda}(L+f-z_p+\sqrt{(x-x_p)^2+z_p^2})} \,\mathrm{d}l \int_{-\Delta y/2}^{+\Delta y/2} e^{-i\frac{2\pi y}{\lambda f}y_p} \,\mathrm{d}y_p$$

$$I(x,y) = \frac{E_0^2}{f^2 \lambda^2} (\Delta y)^2 \frac{\sin^2 \delta}{\delta^2} \left| \int_L e^{-i\frac{2\pi}{\lambda}(\sqrt{(x-x_p)^2 + z_p^2} - z_p)} \, \mathrm{d}x \right|^2$$

ntegration over y and normalizing with flux intensity

$$PSF(x) = \frac{\Delta R}{f\lambda L^2} \left| \int_L e^{-i\frac{2\pi}{\lambda}(\sqrt{(x-x_p)^2 + z_p^2} - z_p)} \, \mathrm{d}l \right|^2$$





$$2\theta \longleftrightarrow \theta(tg2\alpha)$$

SCATTERING

$$\frac{\left(\vartheta_s - \vartheta_i\right)^2}{\frac{1}{2}} + \frac{\varphi_s^2}{\tan\vartheta_i} \approx \frac{f^2\lambda^2}{\cos\vartheta_i \sin\vartheta_i}$$

APERTURE DIFFRACTION

$$I(\vartheta) \propto \frac{\sin^2 \left(\frac{\pi d}{\lambda} \sin \vartheta\right)}{\left(\frac{\pi d}{\lambda} \sin \vartheta\right)^2}$$



ELECTRIC FIELD DIFFRACTED ON THE HYPERBOLA



L. Raimondi, D. Spiga, SPIE Proc., 8147 (2011)

SCATTERING: THEORETICAL APPROACH

- 1. XRS is an effect strongly dependent of the photon energy
- 2. it cannot be simulated using geometrical optics
- 3. the scattering intensity is proportional to the surface PSD (Power Spectral Density of the roughness)

 $dI_s/d\theta_s \alpha PSD$ $\sigma^2 = PSD df$

However, we cannot extend the proportionality to the low frequency range!

4πσsinα < λ e.g. λ=1Å α=0.5° σ<9Å

